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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

are the Application of: **HATTORI, Kazuhiro**

Group Art Unit: 1765

Serial No.: **09/816,784**

Examiner: **Lan Vinh**

Filed: **March 26, 2001**

P.T.O. Confirmation No.: 5542

For: **DRY ETCHING METHOD, MICROFABRICATION PROCESS AND DRY ETCHING MASK**

RESPONSE UNDER 37 CFR §1.116
- EXPEDITED RESPONSE -
GROUP ART UNIT 1765

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 22, 2004

Sir:

In response to the Office Action dated **October 22, 2003**, please amend the above-identified application as follows: